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Performance of the low power heaterless plasma discharge (HPD) cathode for electric propulsion applications in small satellites

L. Conde¹, D. Ramírez¹, A. Gómez¹, J. González² and J.M. Donoso¹

¹ Department of Applied Physics. Escuela Técnica Superior de Ingeniería Aeronáutica y del Espacio. Universidad Politécnica de Madrid (UPM). 28040 Madrid. Spain.

² ARCNL Advanced Center for Nanolithography. Science Park I06 XG, Amsterdam. The Netherlands.

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Motivation : Development of low power cathodes for small/micro satellites

Requisites for cathodes intended for electric propulsion applications in nano and micro satellites (size, electric power, gas consumption ...) *are very demanding*. Hence, the implementation of conventional electron sources based on thermionic electron emission in nano and micro satellites is an issue.

- Thermal stresses are important in *conventional Hollow Cathodes* (HC) where *thermionic electrons* from a heated ($T > 2000$ K) insert material produce the *partial ionization of a neutral gas flow*.
- The new *Heaterless Hollow Cathodes* (HHC) are aimed at avoiding the HCs high temperatures of operation. A high voltage electric discharge is triggered two electrodes in a gas flow. In this case, the *electron thermionic emission is produced by the ohmic heating of electrodes* by the plasma discharge current (see section 5 of reference cited below).

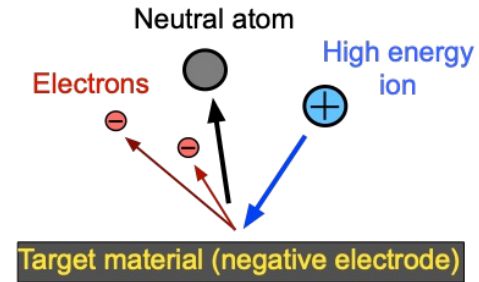
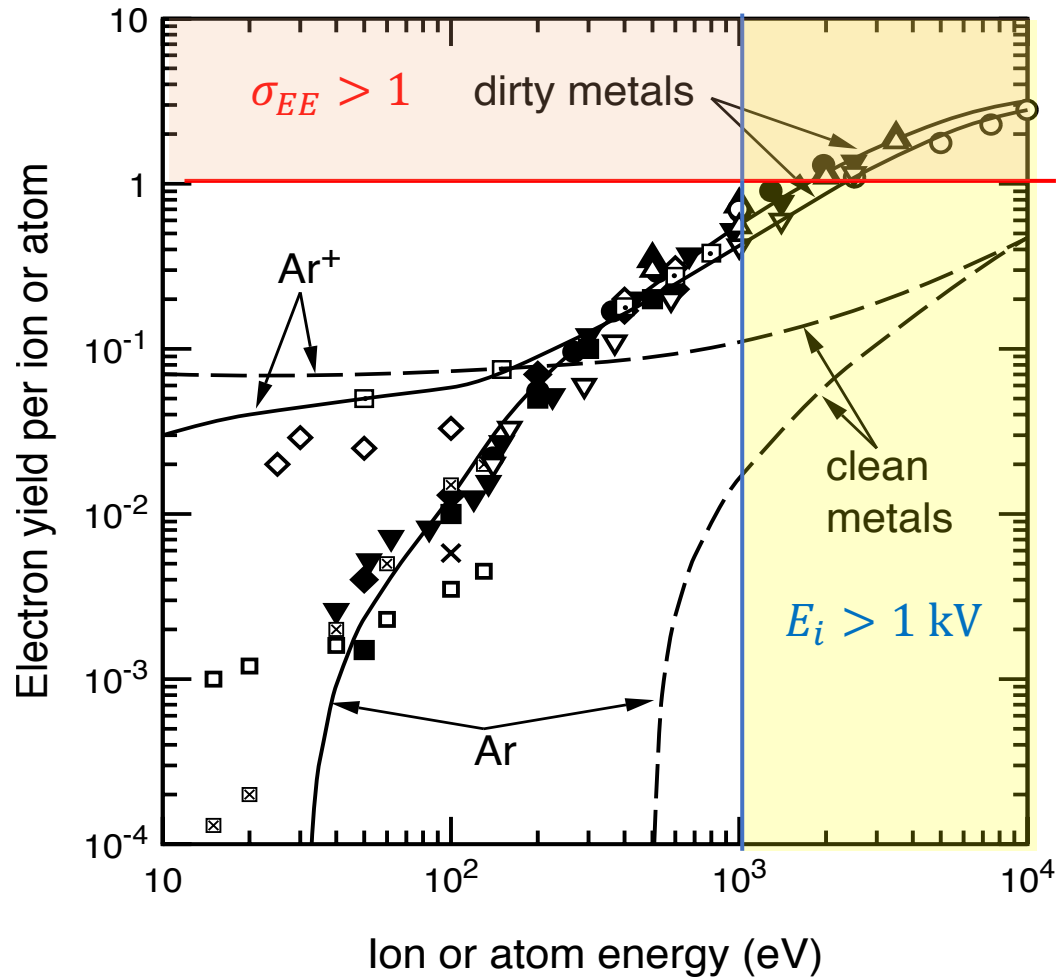
The objectives of present add-on outcome from the NEMESIS project are:

- Explore the replacement of the *secondary electron emission (SEE) by ion impact* as a mechanism to deliver a low current of free electrons
- The development of a *laboratory prototype of a low power cathode* based on SEE.
- The search for additional applications of the CaAl_2Si_2 :e⁻ electrified material compared to LaB_6

D.R. Lev, I.G. Mikellides, D. Pedrini, D.M. Goebel, B.A. Jorns and M.D. McDonald. *Recent progress in research and development of hollow cathodes for electric propulsion*. Rev. Mod. Plasma Phys. **3**:6 (2019).



HPD cathode physical principle : Secondary electron emission by ion impact



- The *production of electrons is driven by the kinetic energy of the ions* impacting a target electrode. Symbols in figure indicate different target materials.
- The yield of electrons per ion σ_{SEE} is a statistical concept that characterizes the average number of emitted electrons produced by the impact of one ion.
- *We need a group of ions with energies in the KeV range to obtain $\sigma_{SEE} > 1$* or production of more electrons than ions are lost.
- *Temperature of target electrode is less relevant* than in thermionic emission and/or hollow cathode discharges.
- However, *SEE electron currents are much lower* than in thermionic emission process.

- A.V. Phelps and Z. Lj. Petrovic. *Cold-cathode discharges and breakdown in Argon: surface and gas phase production of secondary electrons*. Plasma Sources Sci. Technol. **8** (3) R21-R44 (1999). <https://doi.org/10.1088/0963-0252/8/3/201>



The low power heaterless plasma discharge (HPD) cathode/plasma source

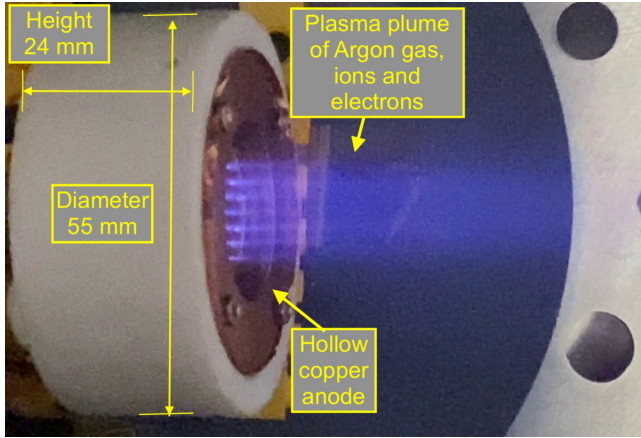


Fig. 1: Upper view HPD cathode in operation inside the vacuum tank

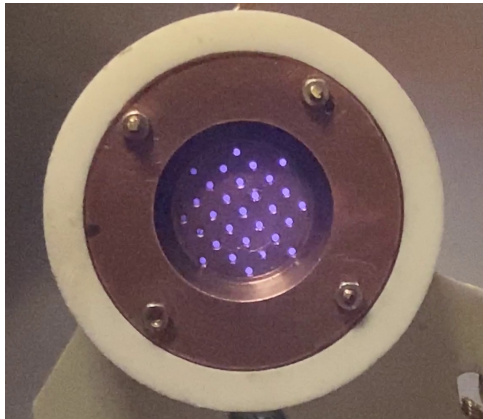


Fig. 2: Front view of HPD cathode in operation inside the vacuum tank

- A plasma is produced by *DC high voltage and low current plasma discharge* between two parallel electrodes in a gas flow.
- Instead of thermionic emission, *electrons are produced by ion impact* at the surface of the electrode connected to a positive voltage. A fraction of electrons leak from the electric discharge to the vacuum tank through the anode holes.
- *Operation temperatures are much lower than with thermionic electron emission* since no electrode heating is needed for the electron emission.
- Consequently, HPD plasma prototype can be made with *simple materials* we have available at hand (teflon body, copper electrodes, ...).
 - 55 mm in diameter and 24 mm of length.
 - Argon mass flow rate $\dot{m} \leq 6$ sccm
 - Background Argon pressure: $p_a = 1 - 3 \cdot 10^{-3}$ mbar
 - No pressure surge is needed to trigger the plasma discharge.
 - DC electric discharge: $V_{ds} = 600 - 1500$ volts : $I_{ds} \sim 3 - 10$ mA
 - Electric power consumption: $P_W = 1.8 - 30$ W



HPD cathode performance : Current-Voltage (IV) characteristic curves

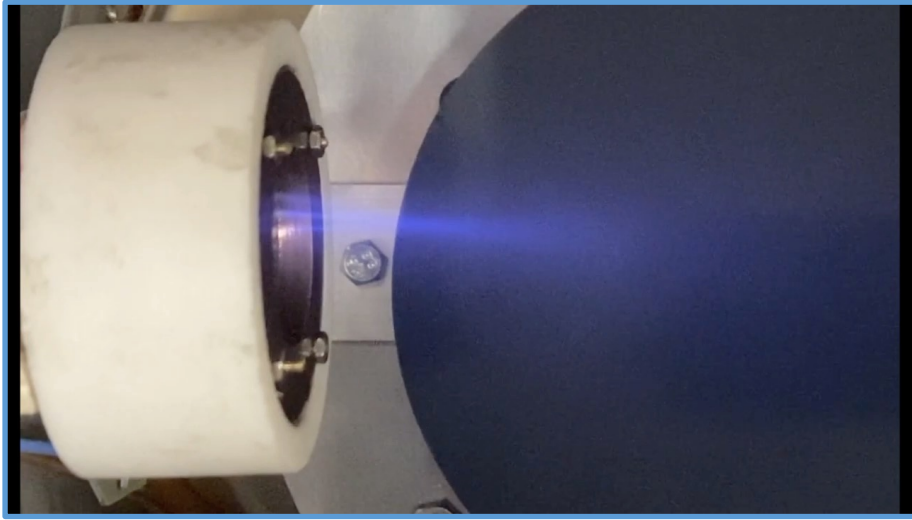


Fig. 4: Plasma plume of the HPD cathode in the experiment of Fig. 6. Real time scale.

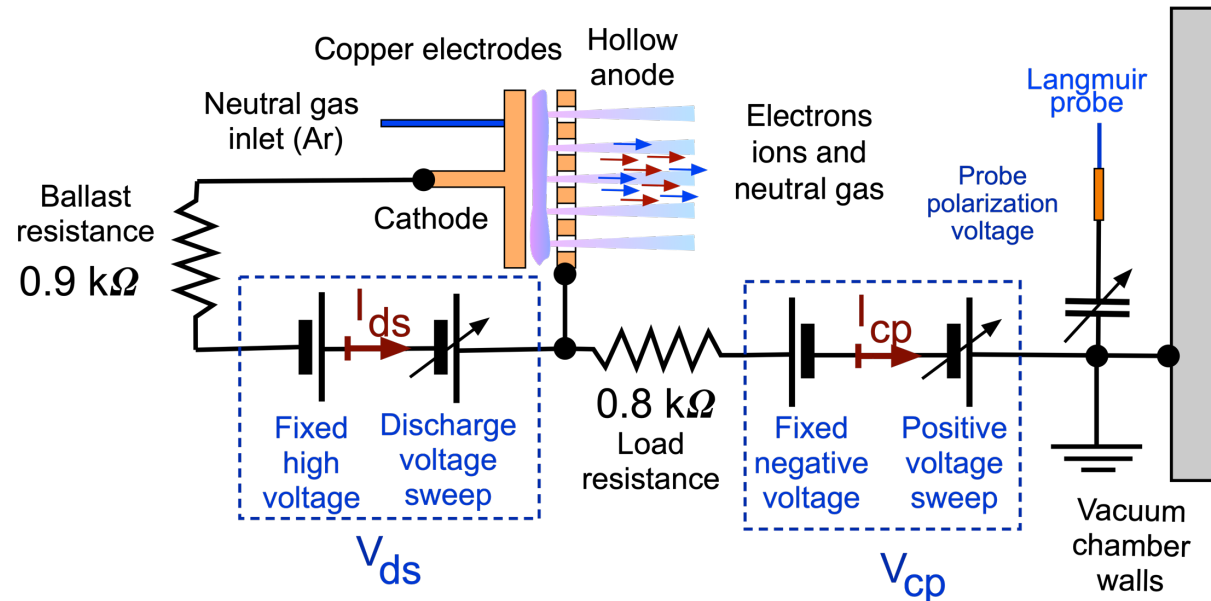


Fig. 5: Electrical scheme of the HPD cathode testing and flow chart for voltage current (IV) $I_{cp}(V_{cp})$ curves.

| Equipment | Characteristics | Function |
|------------------|---|---|
| • FUG | • Power supply 1.5 kV / 1.5 A | • Fixed HPD discharge voltage $V_{ds} \sim 0.6 / 1.5$ kV |
| • Agilent N5771A | • Power supply 300 V / 5 A | • Sweep HPD discharge voltage $V_{ds} \sim 0 / 300$ V |
| • LAB-SP | • Power supply 200 V / 5 A | • Fixed negative HPD polarization voltage $V_{cp} \sim -90 / 0$ V |
| • Agilent N5770A | • Power supply 150 V / 10 A | • Sweep positive HPD polarization voltage $V_{ds} \sim 0 / 300$ V |
| • Keithley 2700 | • Multimeter | • Measurement of $I_{cp}(V_{cp})$ cathode polarization current. |
| • Langmuir probe | • Cylindrical; $\phi = 0.89$ mm, $L = 22.59$ mm. Sweep rate; 200 IV curves per second | |



HPD cathode testing : Understanding the $I_{cp}(V_{cp})$ characteristic curves

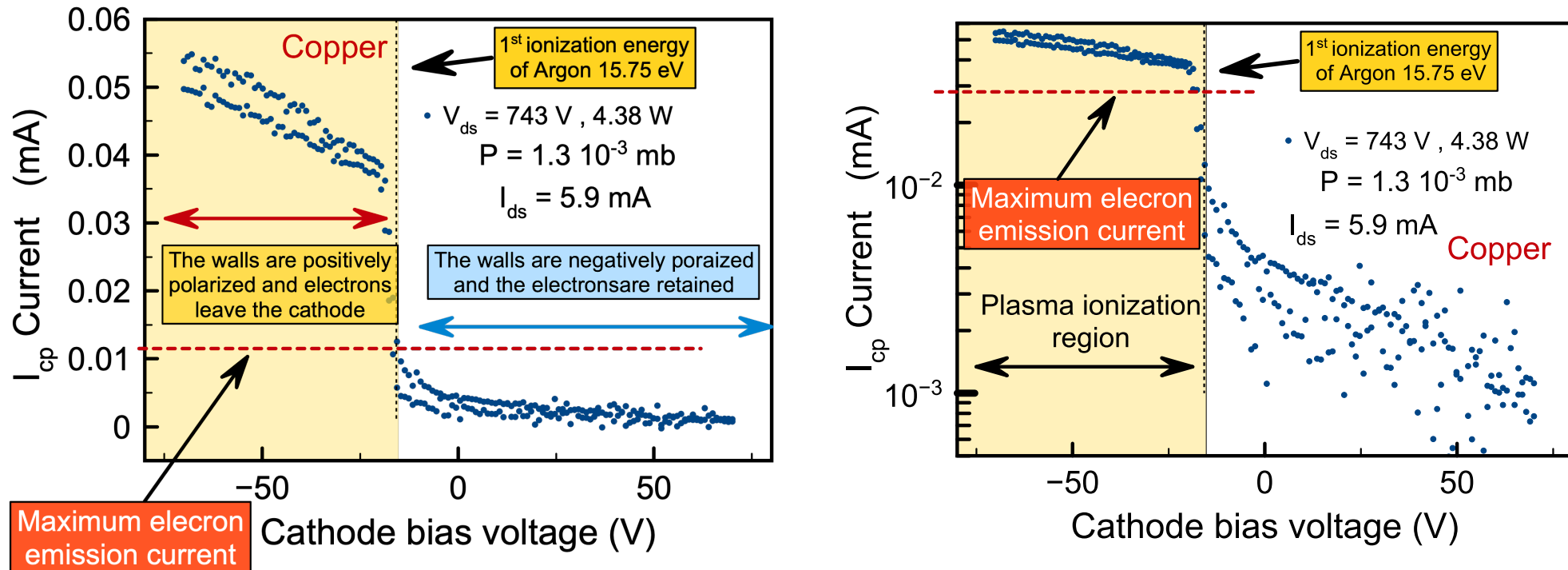


Fig. 5: Typical current voltage characteristic curves for copper in linear and semilogarithmic axes.

- Copper is a reference material with high work function used as a reference in present study.
- The plateau for $V_{cp} \ll -15.76$ V is associated to the *maximum electron emission current* $I_{mx} \sim 0.04$ mA that is a small fraction (below 1%) of the discharge current $I_{cp} \sim 5.9$ mA.

Electron emission performance for copper:

$$\eta = \frac{I_{mx}}{P_W} \simeq \frac{0.02}{4.38} = 0.005 \text{ mA / W}$$



HPD cathode performance : The LaB₆ current-voltage characteristic curves

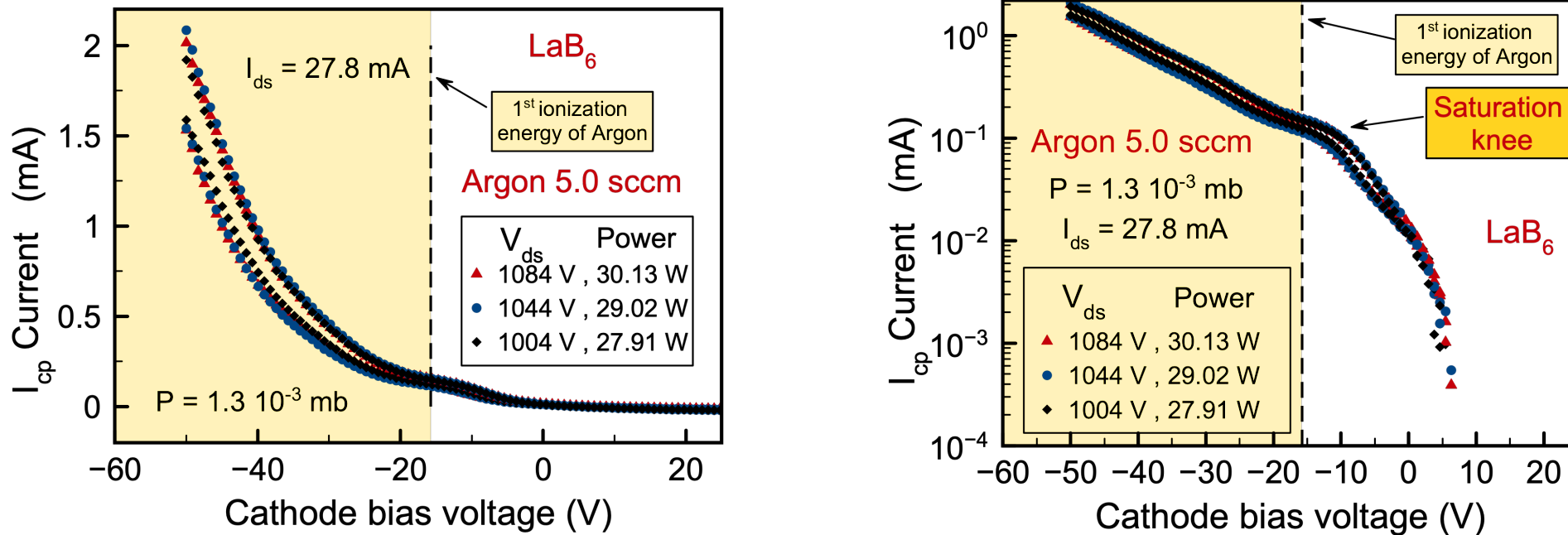


Fig. 6: Typical current voltage characteristic curves for lanthanum hexaboride in linear and semilogarithmic axes.

- Lanthanum hexaboride (LaB₆) has a low work function and then its maximum electron emission currents $I_{mx} \approx 0.2$ mA (saturation knee) are a 5 times higher than for copper.
- Electric power scales up as LaB₆ is involved currents increase.

Electron emission performance for LaB₆:

$$\eta = \frac{I_{mx}}{P_W} \approx \frac{0.2}{28} = 0.007 \text{ mA / W}$$



HPD cathode performance : C12A7:e- current-voltage characteristic curves

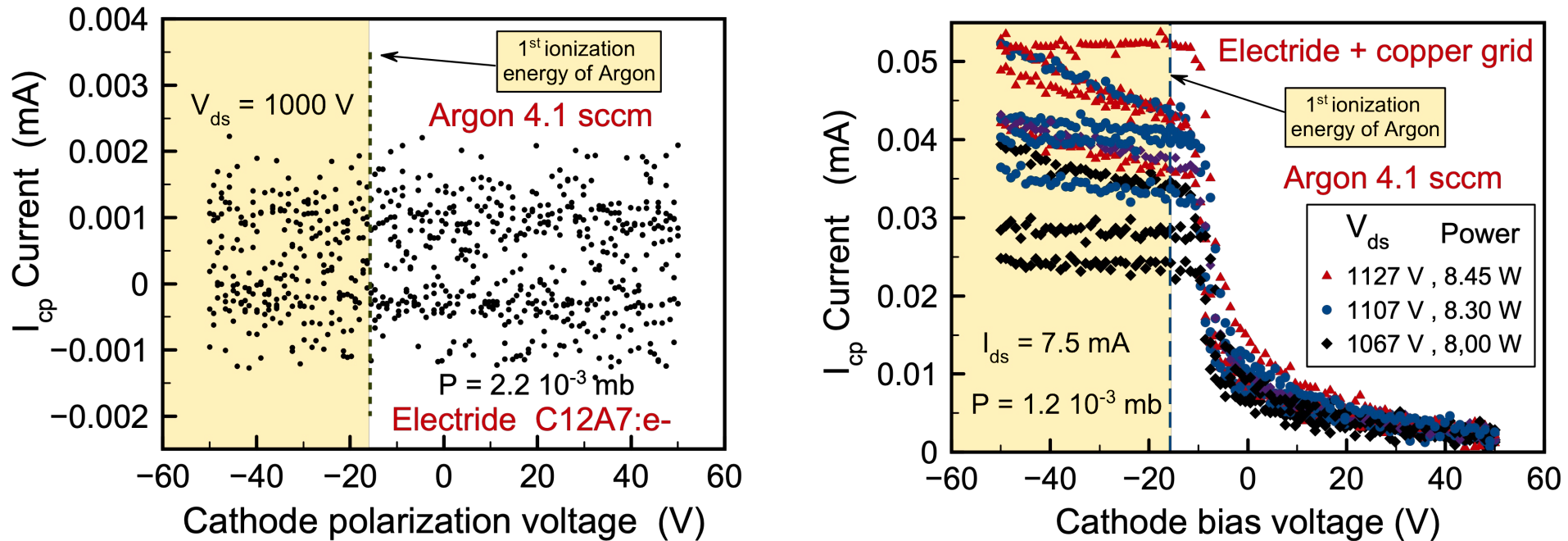
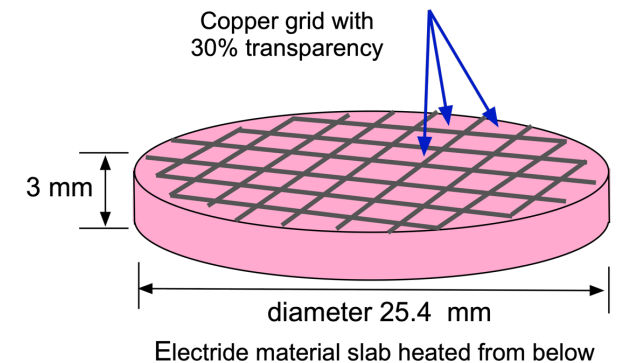


Fig. 7: typical current voltage characteristic curves for C12A7:e- in linear and semilogarithmic axes.

- Initial results for the C12A7:e- electrified material were disappointing.
- A notable improvement was observed if we put a conductive grid on the surface of the material bombarded by the ions.
- The low performance is basically related with the low electric conductivity of the electrified material.



Conclusions and outlook

Positive:

- *Secondary electron by ion impact can be an alternative to* thermionic electron emission when hen required electron currents are low. In our tests, *thermionic emission is negligible* due to *the low temperature of operation*.
- Contrary to conventional hollow cathode discharges, HPD cathode operates with *low currents* and *high voltages* and *low electric power consumption*.
- Low temperatures of operation allow the use of *simple materials* (copper, teflon, ...), there is room for miniaturization using more sophisticated insulators, etc.
- We the HPD cathode delivers higher electron emission currents when *using of a low work function material (such as the $CI2A7$:-e electrude or LaB_6)* for the target (negative) electrode.



Fig. 8: The inner (negative) electrode of copper after few hours of continuous operation

Negative:

- As shows the photograph the *ion bombardment erodes* the surface of the inner (negative) electrode.
- Gas flow and distribution of neutral atoms in these small volumes is not a trivial issue.
- Temperatures of operation must remain low since ohmic heating of electrode can produce the evaporation of material and brings a transition to arc discharge can damage the HPD cathode.

Thank you for you time and interest

